



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT

Arlene
7/15/99
7/a

In re Application of:

Gurtej S. Sandhu

Serial No.: 09/023,146

Filed: February 12, 1998

For: TUNGSTEN SILICIDE (WSL)
DEPOSITION PROCESS FOR
SEMICONDUCTOR
MANUFACTURE

Examiner: Dang, T.

Group Art Unit: 2813

Attorney Docket No.: 3369US (91-365RE)

CERTIFICATE OF MAILING

I hereby certify that this correspondence along with any attachments referred to or identified as being attached or enclosed is being deposited with the United States Postal Service as First Class Mail (under 37 C.F.R. § 1.8(a)) on the date of deposit shown below with sufficient postage and in an envelope addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231.

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Devin R. Jensen
Typed/printed name of person whose signature is contained above

AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

This amendment is in response to the Office Action of March 26, 1999, and Supplemental Office Action of April 7, 1999, the initial period of response to which is set to expire on July 7, 1999.

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IN THE DRAWINGS

Applicant notes the Draftperson's objection to the drawings under 37 C.F.R. § 1.84 and will submit corrected formal drawings upon receipt of a notice of allowability.

07/13/1999 CVORACHA 00000084 09023146

01 FC:103
02 FC:102

270.00 OP
156.00 OP